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**Bib Data Sheet** 

**CONFIRMATION NO. 2337** 

So USC 119 (a-d) conditions well after net verified and Acknowledged Examiner's Signature Initials  ADDRESS  000513  TITLE  Silicon epitaxial wafer and its production method  FILING FEE RECEIVED 920  FEES: Authority has been given in Paper No to charge/credit DEPOSIT ACCOUNT No for following:  DRAWING 2  CLAIMS 6  2  All Fees 1.16 Fees (Filing) 1.17 Fees (Processing Ext. of time) 1.18 Fees (Issue)	SERIAL NUMBE 10/501,672	FILING OR 371(c)  DATE  07/16/2004  RULE	Ó	<b>CLASS</b> 438	GROUP ART UNIT 2812		T UNIT	ATTORNEY DOCKET NO. 2004_1129A		
Foreign Priority claimed  JAPAN 2002-16663 01/25/2002  Foreign Priority claimed  STATE OR COUNTRY JAPAN SHEETS DRAWING 2 SHEETS DRAWING 2 SHEETS DRAWING 2  STATE OR COUNTRY JAPAN 2  STATE OR COUNTRY JAPAN 2  ADDRESS  000513  TITLE  Silicon epitaxial wafer and its production method  FILING FEE RECEIVED 920  FEES: Authority has been given in Paper to charge/credit DEPOSIT ACCOUNT No for following:	Hiroshi Take	чта ********* АТА	*	1/17/2003						
35 USC 119 (a-d) conditions	** FOREIGN APPL	ICATIONS ************************************								
TITLE Silicon epitaxial wafer and its production method  FILING FEE RECEIVED 920  FEES: Authority has been given in Paper to charge/credit DEPOSIT ACCOUNT No for following:    All Fees	35 USC 119 (a-d) conditions yes no Met after Met Allowance			COUNTRY	DRAWING		CLAIMS			
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